



MEMS Deformable Mirrors for Adaptive Optics

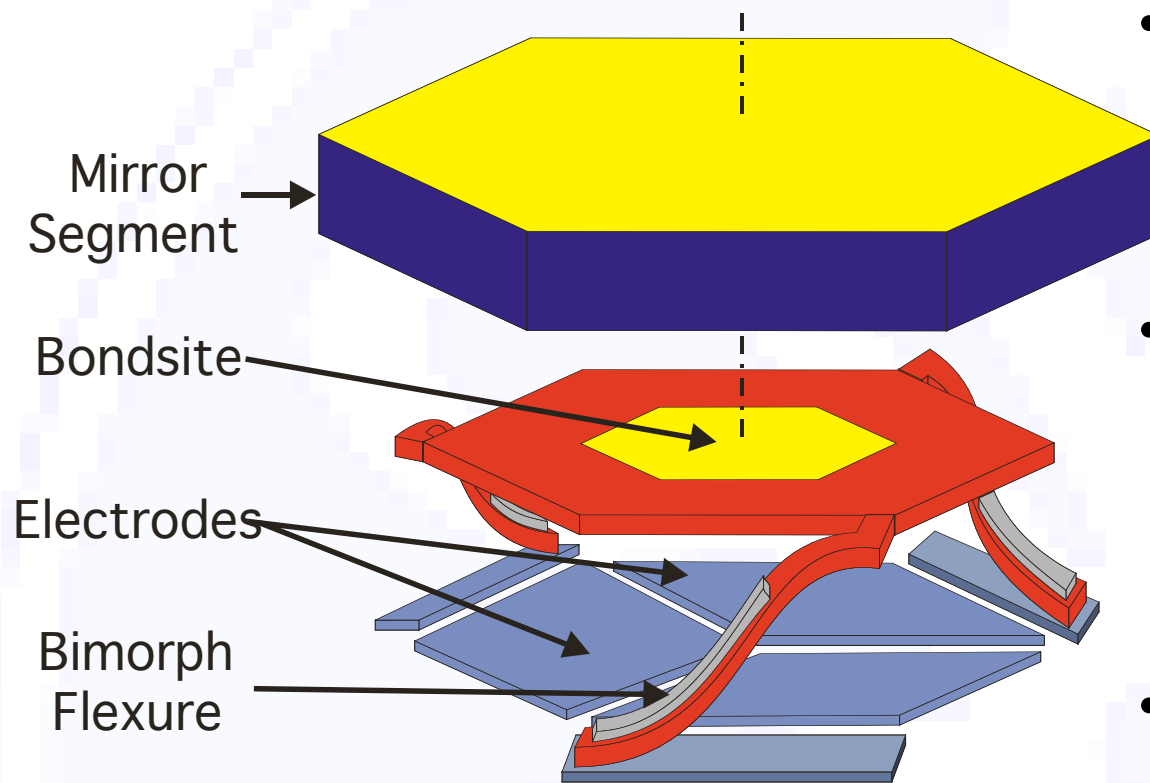
Nathan Doble

Iris AO, Inc

CfAO TMT MEMS DM Workshop - August 19, 2004



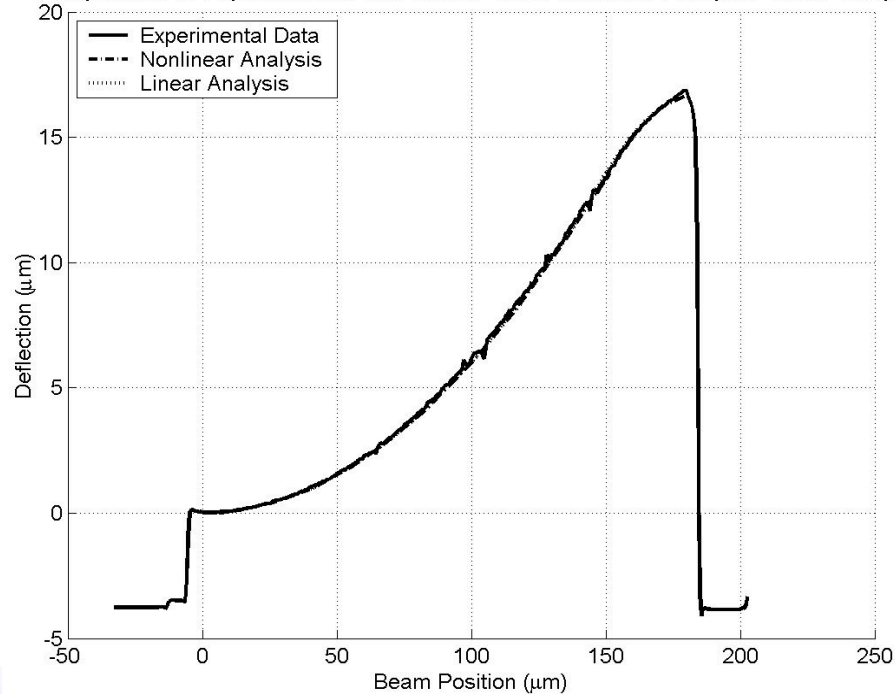
Iris AO MEMS Segmented DM



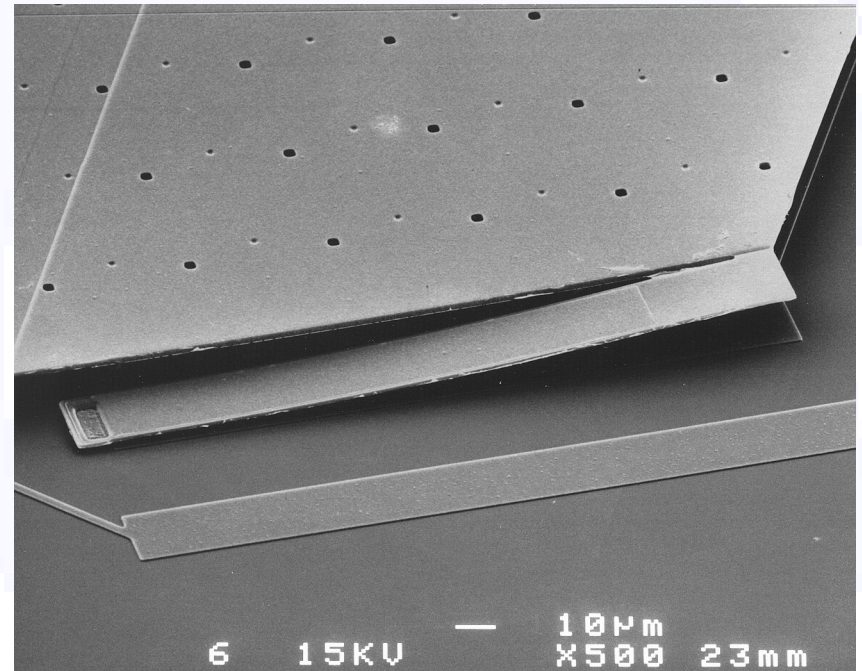
- Robust assembled mirror surface stays flat
- Temperature insensitive bimorphs elevate mirror above substrate
- Piston/tip/tilt electrostatic actuation



Comparison of Experimental, and Linear- and Nonlinear-Analysis Beam-Shape



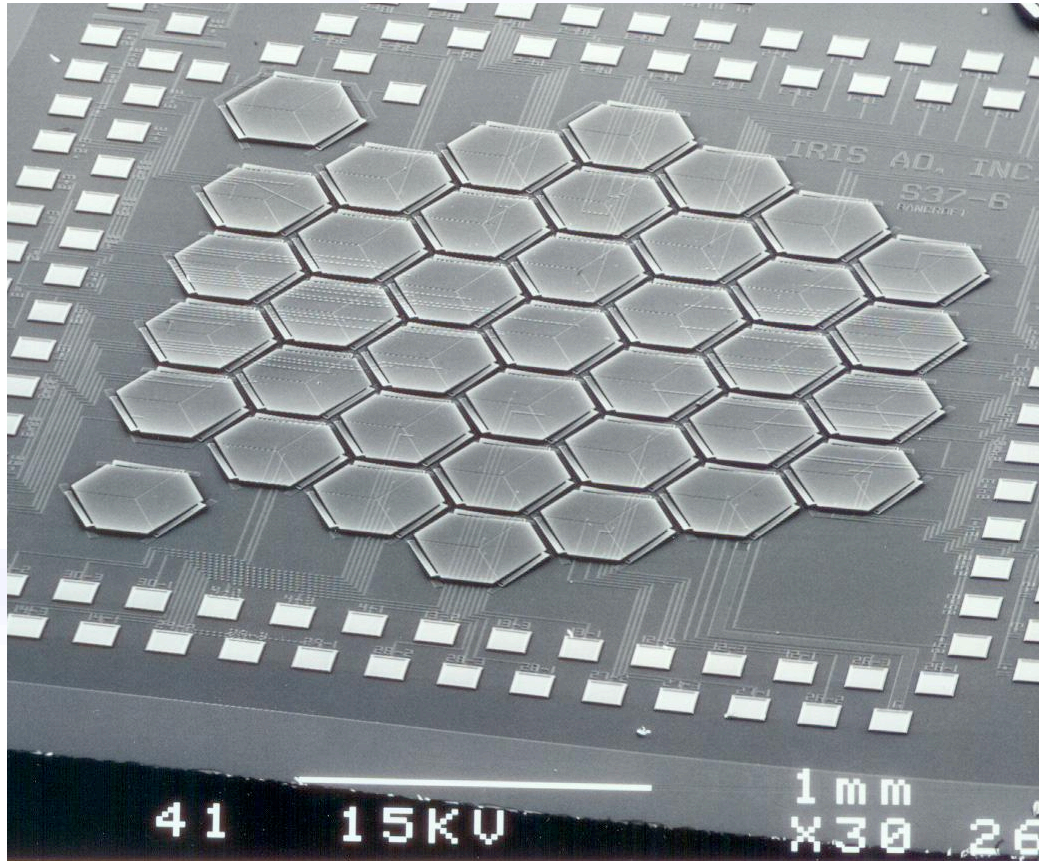
Bimorph Flexures



- Engineered stresses create beam shape
- Stroke determined by design, not process



DM Electrostatic Actuators

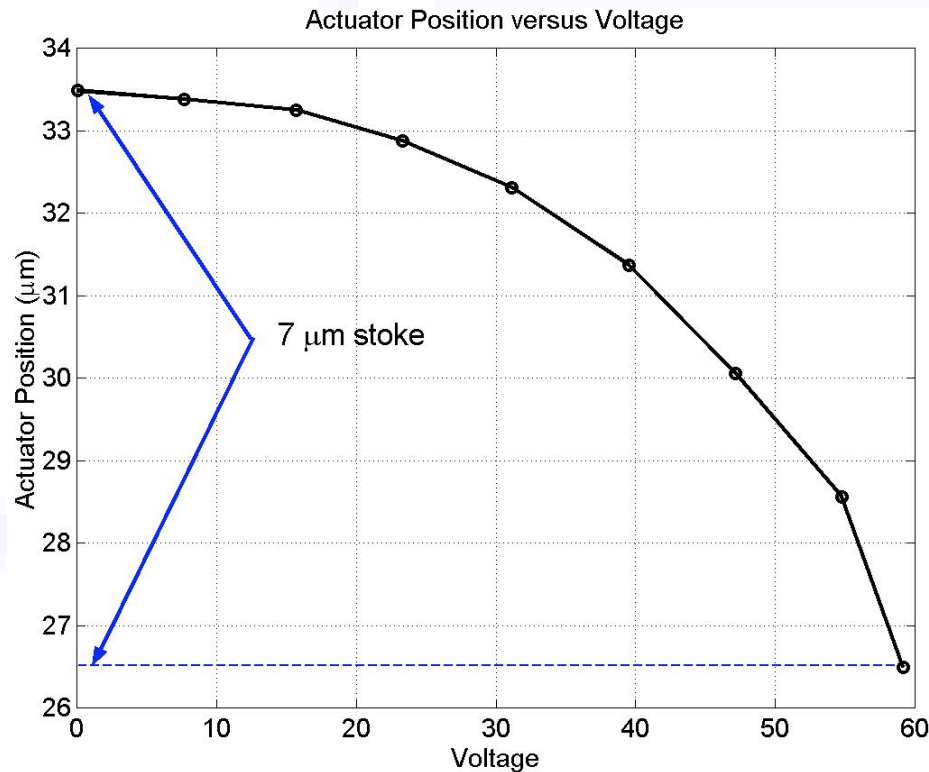


- Actuators wired to periphery
- Electrostatic forces pull actuators down
- No hysteresis
- 4.2 mm aperture



Iris AO, Inc.

DM Stroke: *Position versus Voltage*



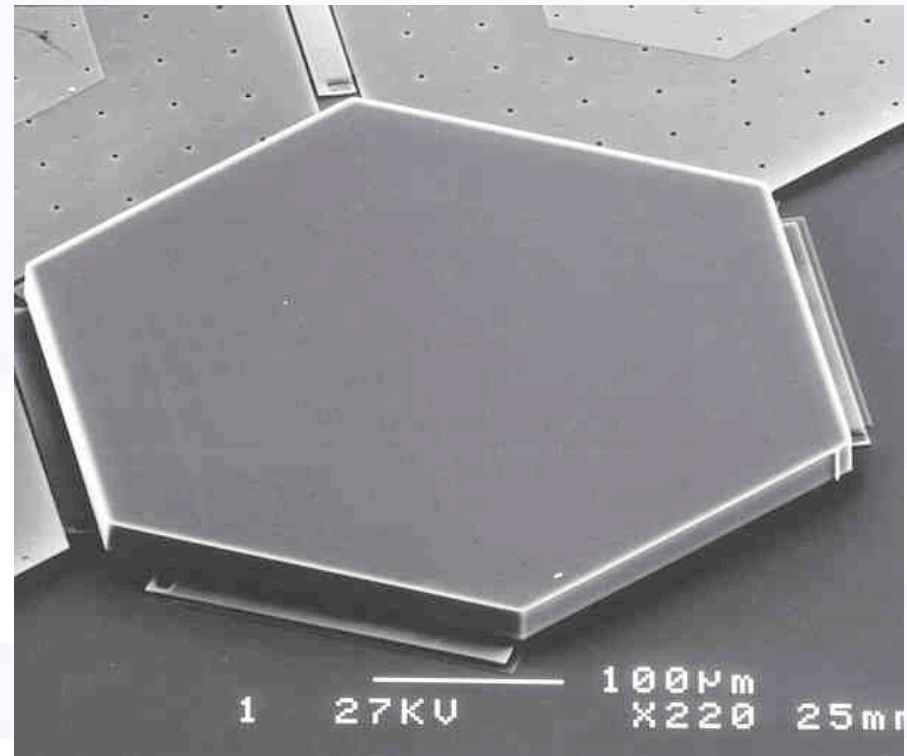
- Design flexibility to trade off stroke, voltage and frequency
- Stroke of up to 20 μm
- Low voltage actuation

- High positioning repeatability



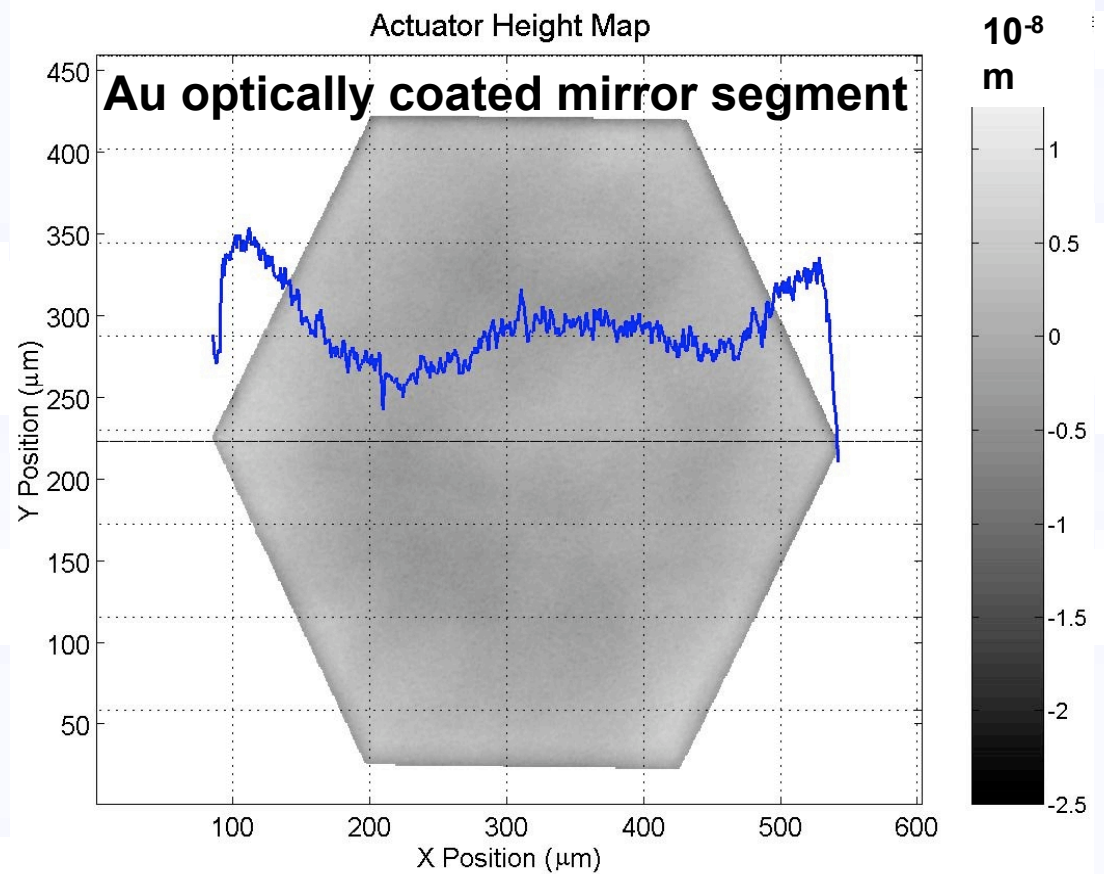
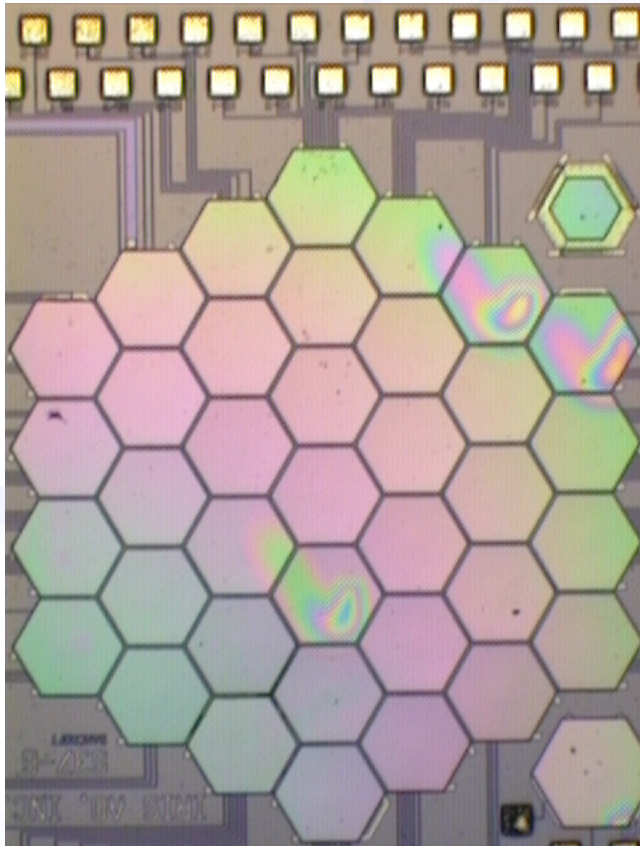
Assembled SOI Mirrors: Benefits

- Single crystal mirror has excellent flatness
- Thickness gives rigidity
 - Mirror is still flat after optical coating
 - Stays flat over varying operating conditions
 - Temperature
 - Actuation
- High fill factor
 - Mirrors cover bimorph flexures
 - Etch holes not necessary





Assembled-Mirror Flatness

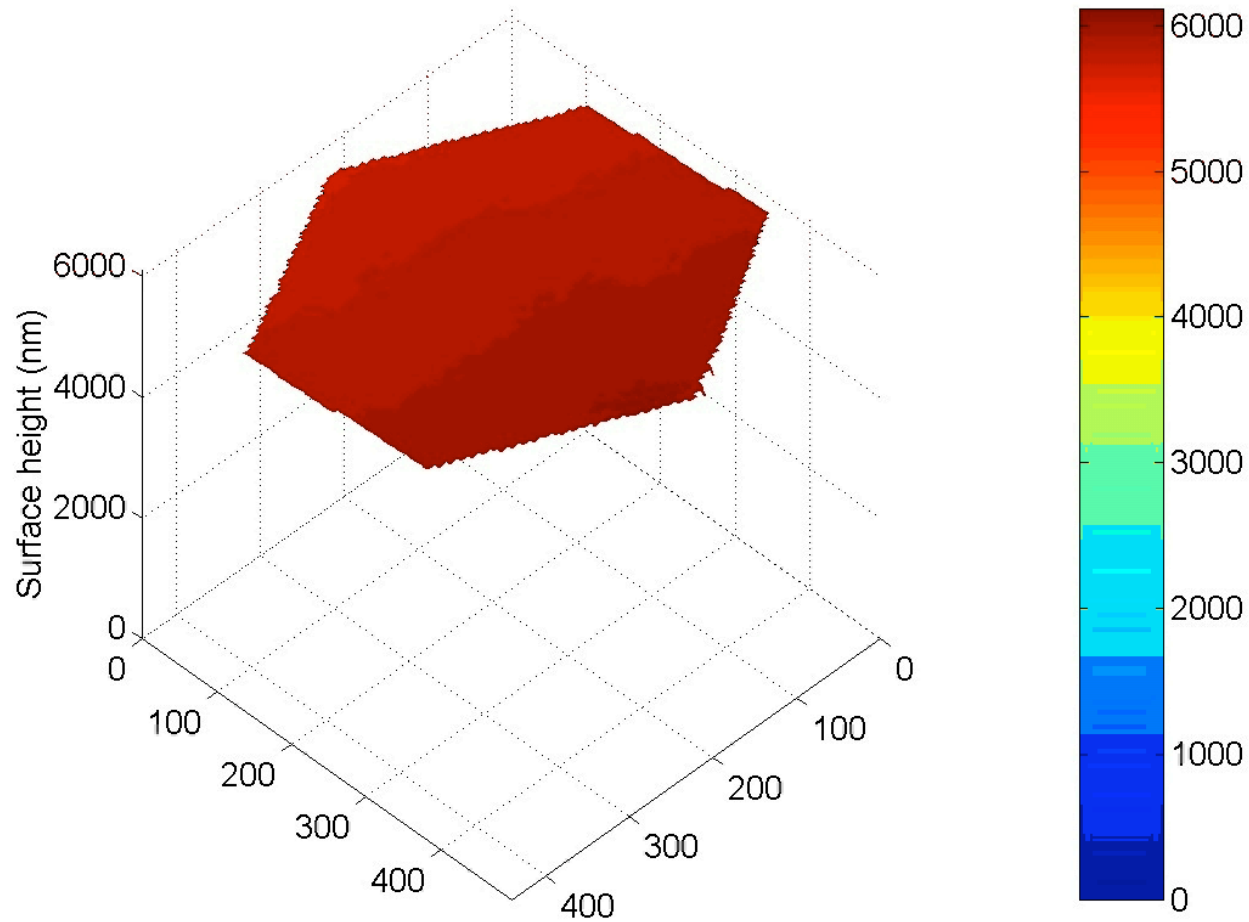


- Low rms surface errors
- < 8 nm rms on average



Iris AO, Inc.

Experimental Deflection (400Hz)



August 19th, 2004

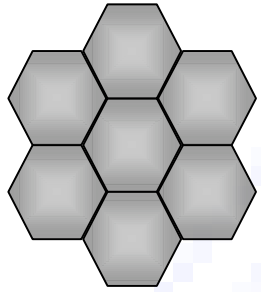
CfAO MEMS workshop

8

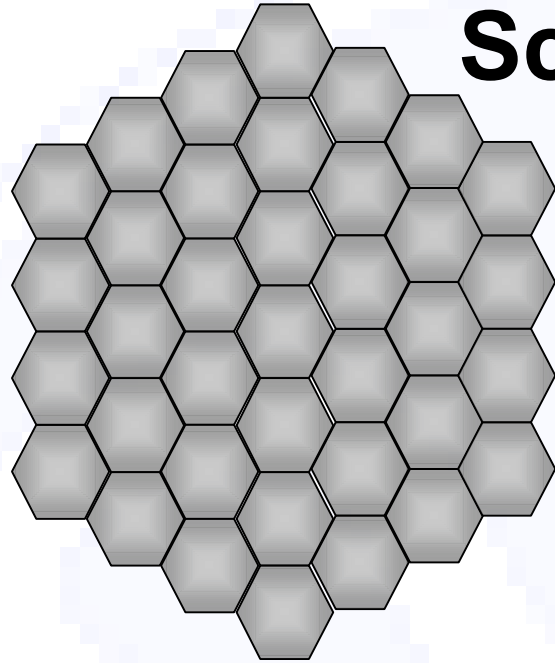


Iris AO, Inc.

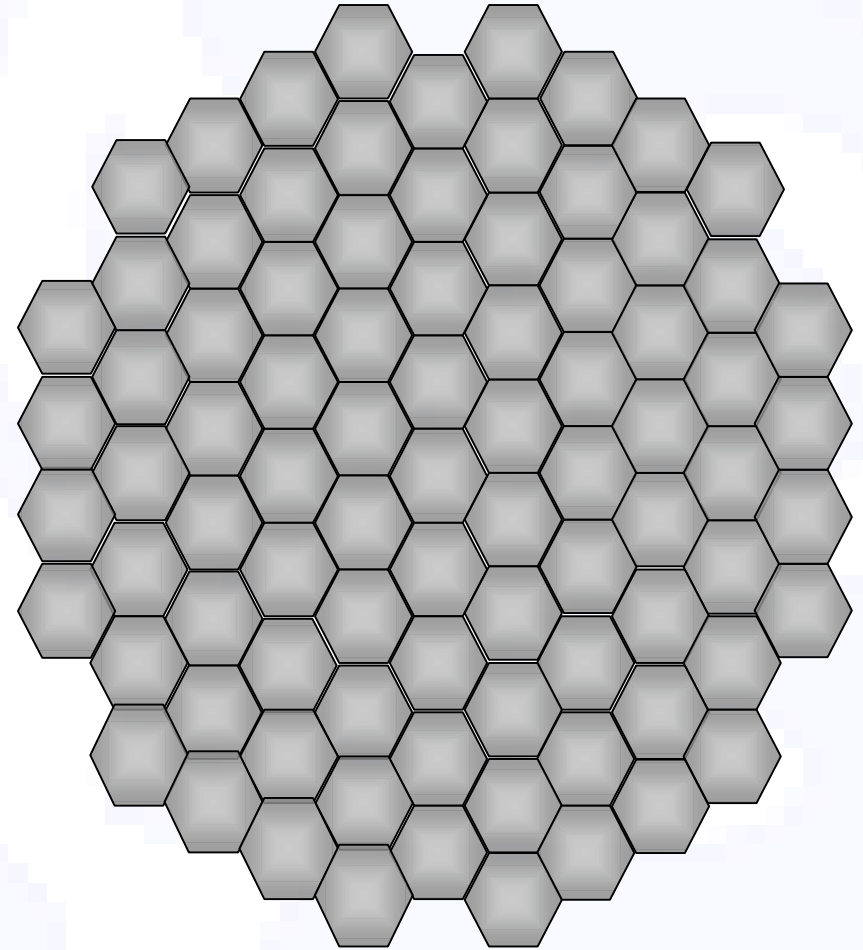
Scalable Architecture



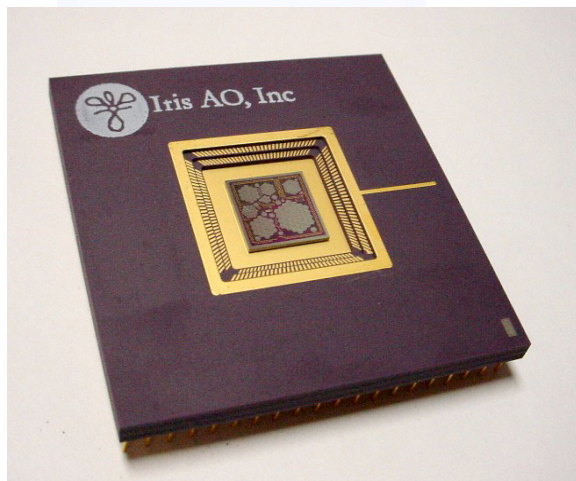
Hearst



Bancroft



Claremont



CfAO MEMS workshop